## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: OZAKI, Takashi, et al.

Group Art Unit: 1792

Serial No.: 10/528,137

Examiner: MACARTHUR, Sylvia

Filed: December 12, 2005

P.T.O. Confirmation No.: 2307

SUBSTRATE PROCESSING APPARATUS AND METHOD FOR For.

MANUFACTURING A SEMICONDUCTOR DEVICE

PETITION FOR EXTENSION OF TIME

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

March 9, 2010

Sir:

Applicants petition the Commissioner for Patents to extend the time for response to the Final Office Action dated November 13, 2009 for one month, from February 13, 2010 to March 13, 2010.

The Commissioner is authorized to charge our Deposit Account in the amount of \$130.00 to cover the cost of the extension for a large entity. In the event that any additional fees are due in connection with this paper, please charge our Deposit Account No. 01-2340.

Respectfully submitted,

KRATZ, OUDITOS & HANSON, LLP

Agent for Applicant Reg. No. 40,899

INB/ak

Atty. Docket No. 050161 Suite 400 1420 K Street, N.W. Washington, D.C. 20005 (202) 659-2930

PATENT & TRADEMARK OFFICE